IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 10/664,739
Filing Date . . . . September 18, 2003
Inventor . . . . Sujit Sharan et al.
Assignee . . . . Micron Technology, Inc.
Group Art Unit 2818
Examiner . . . . Dung Le
Attorney's Docket No. MI22-2340
Title: Methods for Conditioning Surfaces of Polishing Pads After
Chemical-Mechanical Polishing

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT
References –See Attached Form PTO-1449

The Examiner's attention is directed to the references which are listed on

the attached Form PTO-1449, copies of which are attached. No admission is

made regarding whether all the submitted references are prior art.

Citation of the referenced art is respectfully requested.
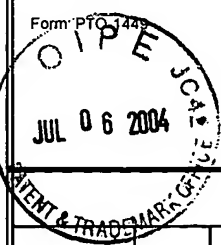
Respectfully submitted,

Dated: July 6, 2004

By: Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

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Form PTO 1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-2340		SERIAL NO. 10/664,739
	LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)		APPLICANT Sujit Sharan et al.		
			FILING DATE September 18, 2003		GROUP 2818

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,786,272	7/28/1998	Marangon et al.			
	AB	5,308,950	5/3/1994	Ramm et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation Yes	Translation No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		
	AS		
	AT		

EXAMINER	DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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